

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Yee-Chung Fu
Assignee: Advanced Nano Systems, Inc.
Amended Title: MEMS Scanning Mirror with Trenched Surface and Tapered Comb Teeth for Reducing Inertia and Deformation
Serial No.: 10/779,952 Filing Date: February 13, 2004
Examiner: Allan R. Wilson Group Art Unit: 2815
Docket No.: ANS-P105

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San Jose, California
October 3, 2005

Special Processing Submission
Mail Stop Petition/Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REQUEST FOR CONTINUED EXAMINATION (RCE) UNDER 37 C.F.R. §1.114


Dear Sir:

This is a Request for Continued Examination (RCE) under 37 C.F.R. §1.114 of the above-identified application.


Please enter the attached Amendment before continuing the examination.

The RCE fee of \$395 required under 37 C.F.R. §1.17(e) is authorized to be charged to our credit card.

Please contact the undersigned attorney with any questions concerning this request in the above-identified patent application.

Certification of Facsimile Transmission	
I hereby certify that this paper is being facsimile transmitted to the U.S. Patent and Trademark Office on the date shown below.	
 Signature	<u>10/3/05</u> Date

Respectfully submitted,


David C. Hsia
Attorney for Applicant(s)
Reg. No. 46,235